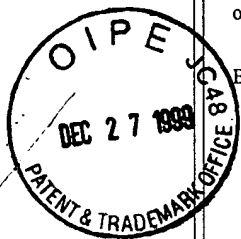


I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail in an envelope addressed to:  
Assistant Commissioner for Patents Washington, D.C. 20231  
on December 20, 1999

**PATENT**  
Attorney Docket No.: AM 2119/T21300  
TTC No. 16301M-021300US



By: Lynda Rolisch

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re application of: Karl Littau et al.

Examiner: R. Zervigon

Application No.: 08/893,917

Art Unit: 1763

Filed: July 11, 1997

PETITION TO EXTEND TIME

For: REMOTE PLASMA CLEANING  
SOURCE HAVING REDUCED  
REACTIVITY WITH A SUBSTRATE  
PROCESSING CHAMBER

Assistant Commissioner for Patents  
Washington, D.C. 20231

Sir:

Applicants petition the Assistant Commissioner of Patents to extend the time for response to the Office Action mailed August 24, 1999 for one (1) month, from November 24, 1999 to December 24, 1999. An appropriate response in the form of an Amendment is enclosed herewith.

Please charge the fee of \$110.00 to the undersigned's Deposit Account No. 20-1430. Please charge any additional fees or credit overpayment to the above deposit account. This petition is submitted in triplicate.

Respectfully submitted,

Chun-Pok Leung  
Reg. No. 41,405

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